

# Atmospheric neutron testing of GaN power devices

Mario Sacristan Barbero (SY-STI-BMI R2E)  
Ruben Garcia Alia (SY-STI-BMI R2E)  
Maria Kastriotou (ChipIR)  
Carlo Cazzaniga (ChipIR)

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Science & Technology Facilities Council

ISIS

# Outline

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- Radiation effects on Power Transistors.
  - SEE and Cumulative effects in Si MOSFETs.
  - SEB in Si MOSFETs.
  - Why Wide Band-Gap devices?
  - Previous testing of SiC and GaN.
- Neutron testing of GaN HEMTs at ChipIR.
  - Test setup and DUTs.
  - Destructive and partially destructive SEE.
  - Cumulative effects.
- Conclusions and future work.

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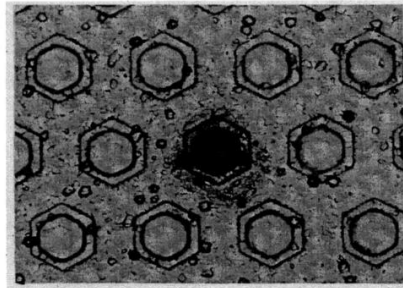
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**PRELIMINARY**

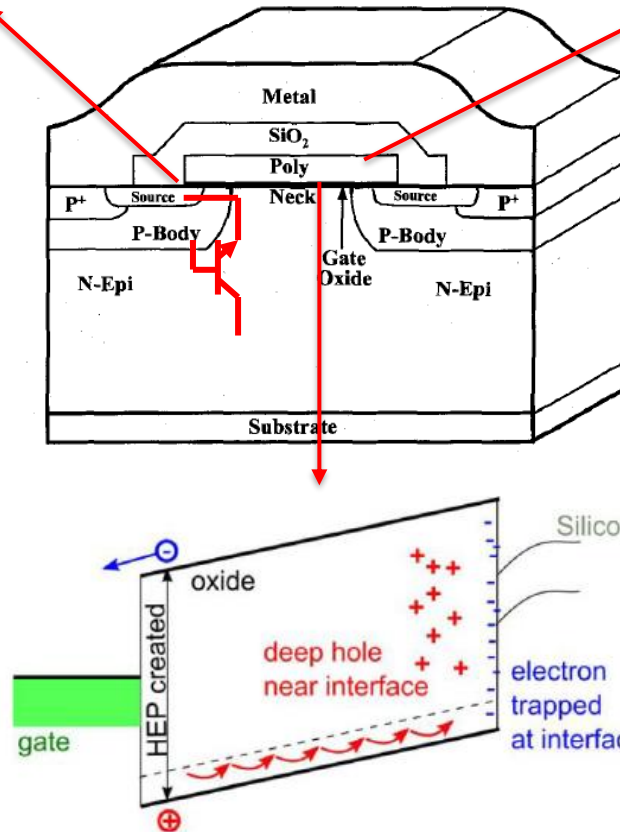
# SEE and Cumulative effects in Si MOSFETs.

**Single Event Burnout (SEB):** due to the parasitic bipolar transistor, a **regenerative current** can be established **leading to burnout** (not typical of PMOS).

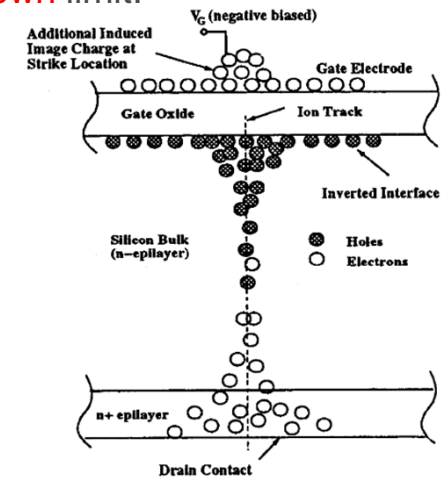


E.G. Stassinopoulos et al. IEEE TNS 39(6), 1992

**Leakage current increase:** decrease of the sub-threshold slope, **increasing the current** for  $V_g = 0$ .



**Single Event Gate Rupture (SEGR):** induced charges close to the oxide can generate **electric field exceeding the breakdown limit**.



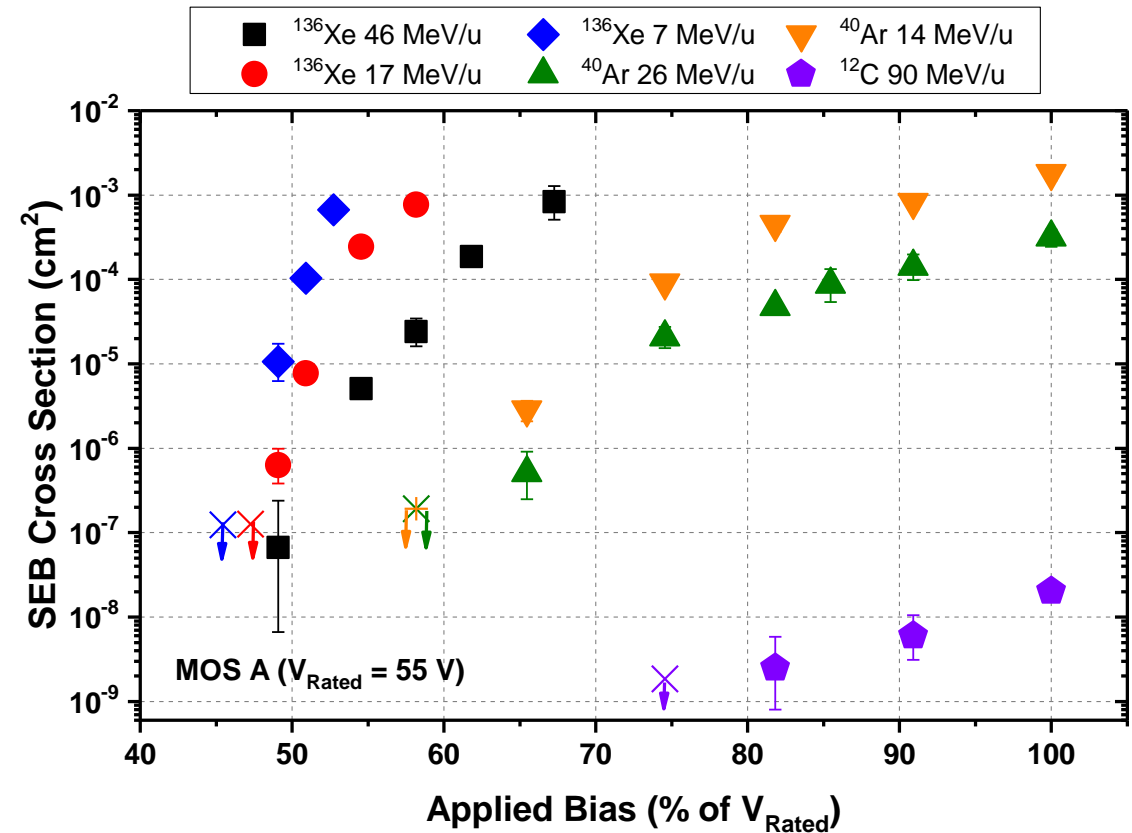
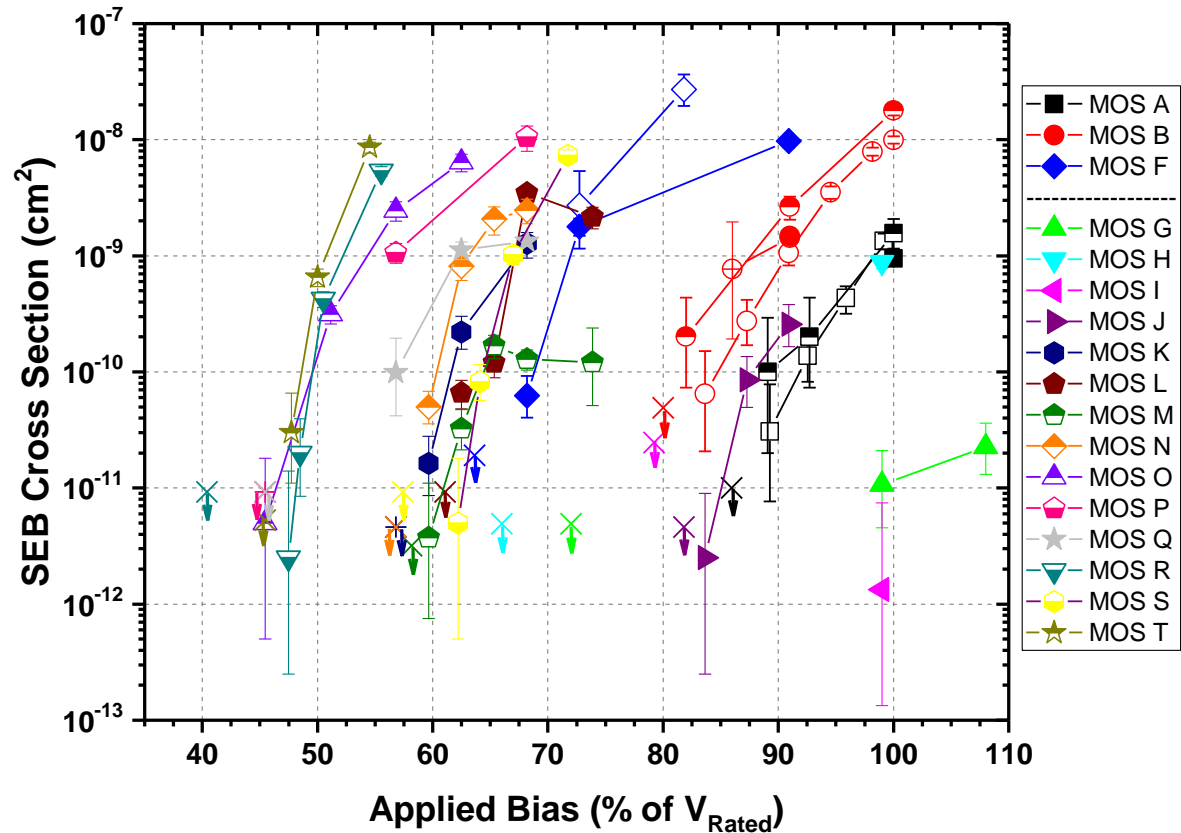
F.W. Sexton, IEEE TNS 50(3), 2003

**Threshold voltage shift:** due to the trapped interface charges, threshold voltage is reduced, hence **easier to turn ON**.

**Displacement Damage** is less relevant in MOSFET than in bipolar technology due to its majority carrier technology, for typical fluences of LHC tunnel. At fluences higher than  $10^{14}$  p cm<sup>-2</sup> **displacement damage increases  $R_{on}$**  due to impurities in the channel.

# SEB in Si MOSFETs

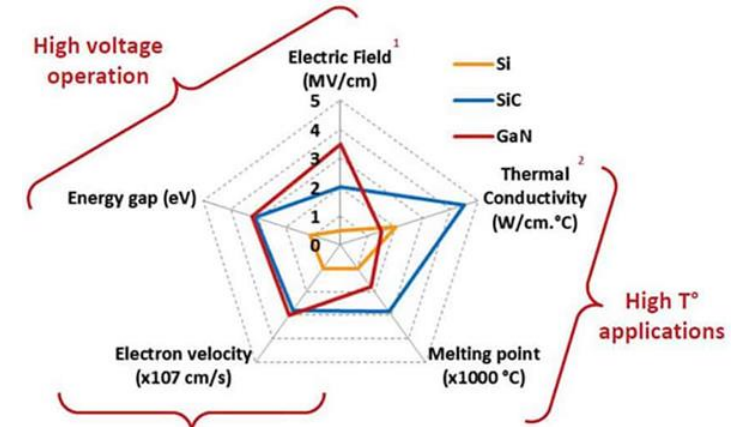
Test of several COTS MOSFETs at same energies and different LET



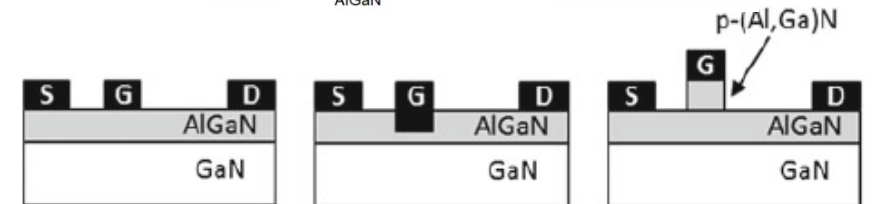
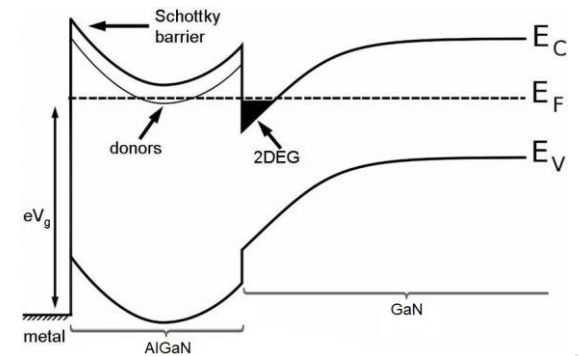
2020, P. Fernández-Martínez

# Why Wide Band-Gap devices?

- Wide band-gap semiconductors (SiC, GaN) allow devices to operate at **higher voltages, temperatures and frequencies**.
- Wider band-gap implies **less generated carriers** and higher field and temperature limits **reduce microscopic cumulative damages**.
- SiC MOSFETs** have proved enhanced **tolerance against SEE** and **less TID** susceptibility.
- GaN HEMTs** rely on a **high mobility 2DEG electron channel** generated in the AlGaN/GaN heterojunction, instead of a MOS capacitors at MOSFETs, therefore:
  - SEE tolerance:** wide band-gap semiconductor, lack of parasitic bipolar.
  - TID tolerance:** no oxide layers.
  - DD tolerance:** majority carrier technology.



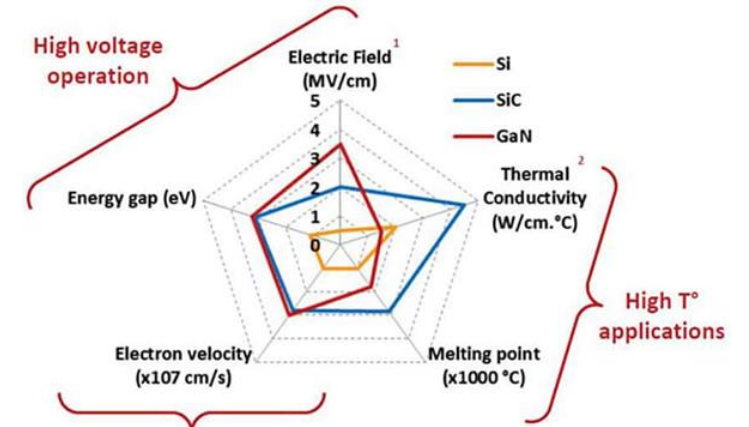
High Frequency switching



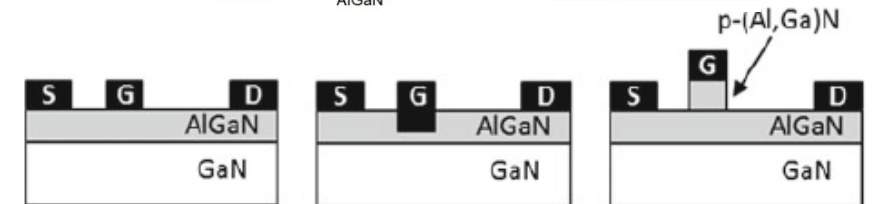
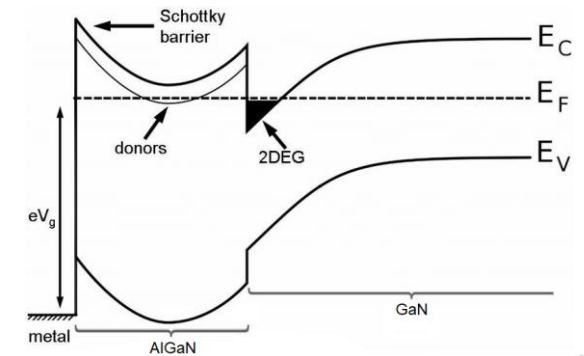
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TO BE VERIFIED



High Frequency switching



# Previous testing of SiC and GaN

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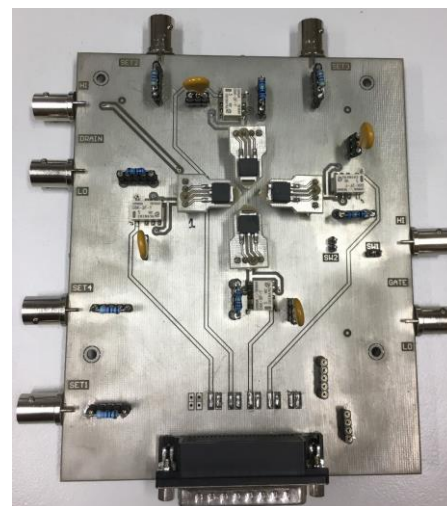
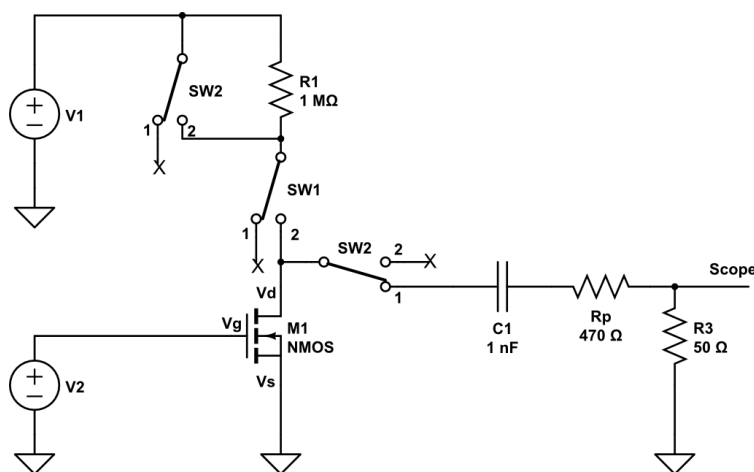
- **CERN:** Extensive work by C. Martinella with SiC MOSFET concerning SEB and SELC (see previous presentation).
- SiC MOSFETs at **RADSAGA:**
  - CHARM: SEB cross section for CREE C3M0120090D at  $3.1e-10 \text{ cm}^2$  @850V. Fluence  $2e9 \text{ n/cm}^2$ .
  - ChipIR: SEB cross section for CREE C3M0120090D at  $4.5e-11 \text{ cm}^2$  @750V. Fluence  $2e11 \text{ n/cm}^2$ .
- Further studies suggest **TID damages are still present.**

S. Gerardin, 2013, “Radiation performance of new semiconductor power devices for the LHC experiment upgrades”
- GaN HEMTs at **RADSAGA:**
  - GANIL: SEBs detected at 83 and 100%  $V_{ds,max}$ , 12 PGA26E19BA DUTs. Fluence  $3e6 \text{ i/cm}^2$ .
  - CHARM: No events up to  $2e9 \text{ n/cm}^2$ , 20 EPC2012 DUTs and 20 PGA26E19BA DUTs.
  - ChipIR: No events up to  $1.5e11 \text{ n/cm}^2$ , 48 PGA26E19BA DUTs.



# Test setup and DUTs at ChipIR

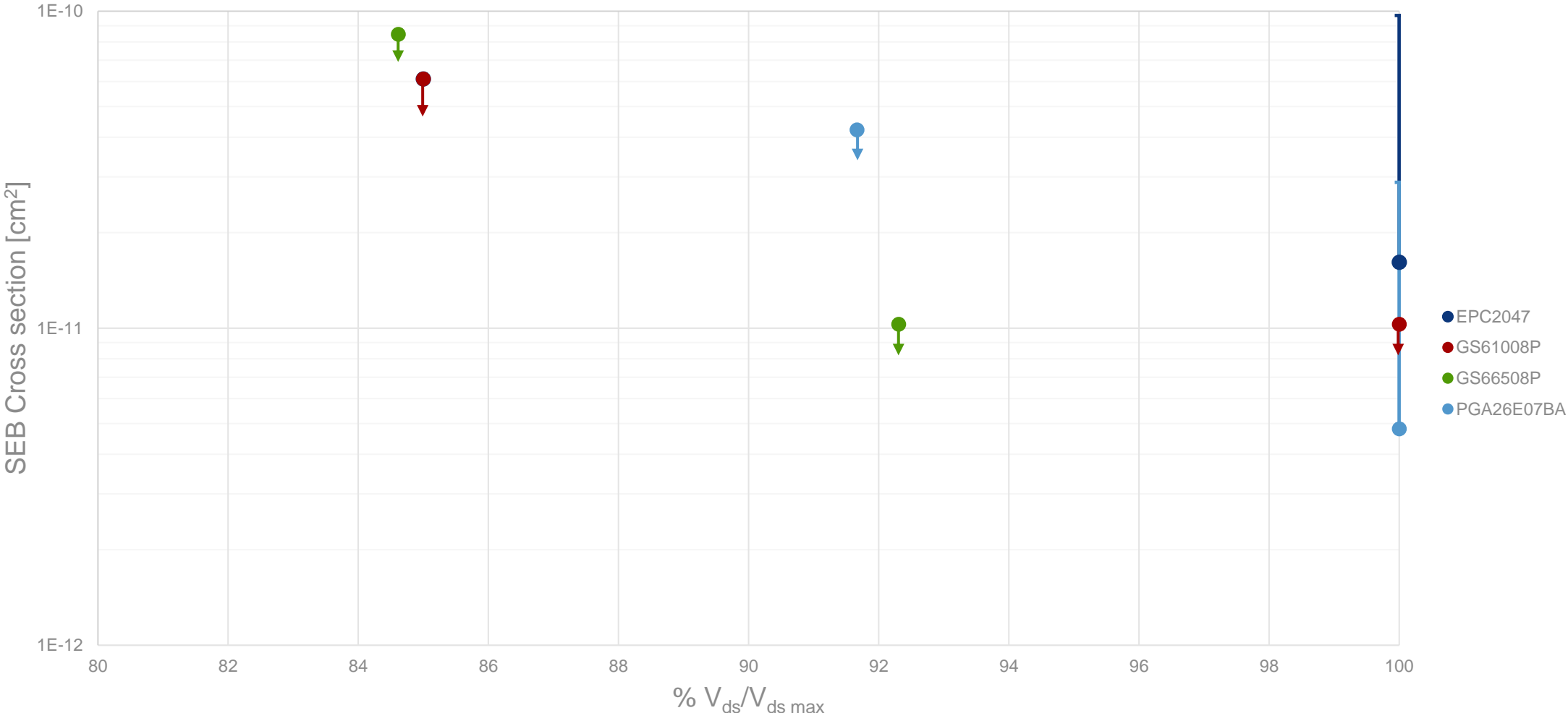
- **4 references** tested (100V and 600V). x2 DUTs of each reference.
- Irradiation board provides **protective system in case of destructive event** and device **characterisation of I-V curves**.
- DUTs **monitored in two ways**: drain/gate total current consumption and drain transients monitored via oscilloscope.
- Test performed remotely with the on-site assistance of our colleagues Maria Kastriotou and Carlo Cazzaniga from ChipIR.



Reference	Technology	$V_{ds,max}$ [V]	$V_{ds,test}$ [V]
EPC2045	GaN HEMT	100	100
GS61008P	GaN HEMT	100	100
PGA26E07BA	GaN HEMT	600	600
GS66508P	GaN HEMT	650	600

# Destructive and partially destructive SEE

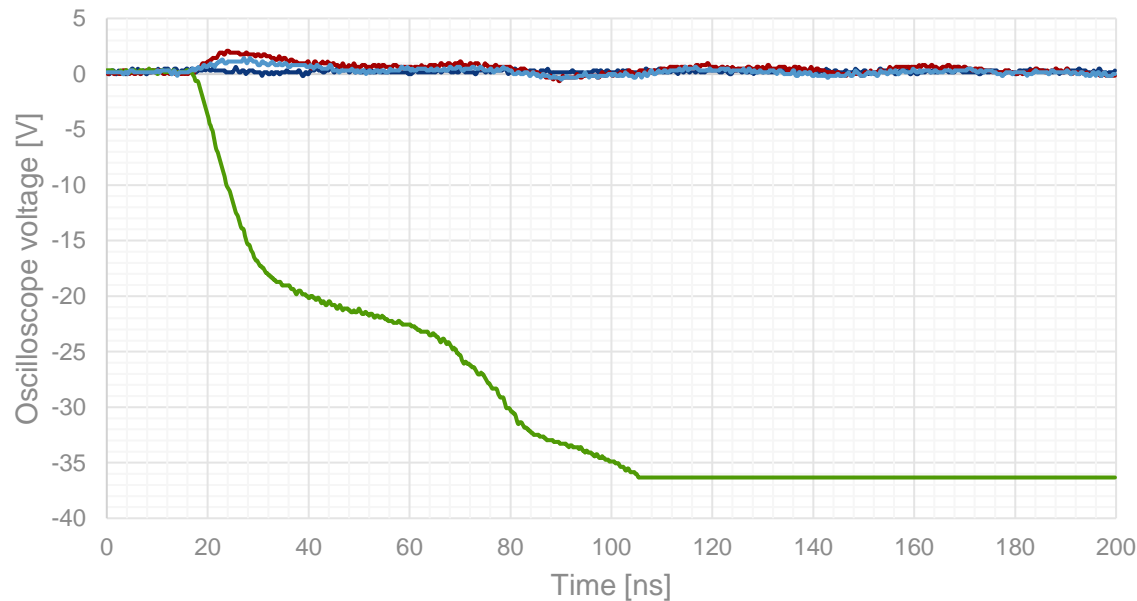
Permanent events GaN HEMTs Cross section



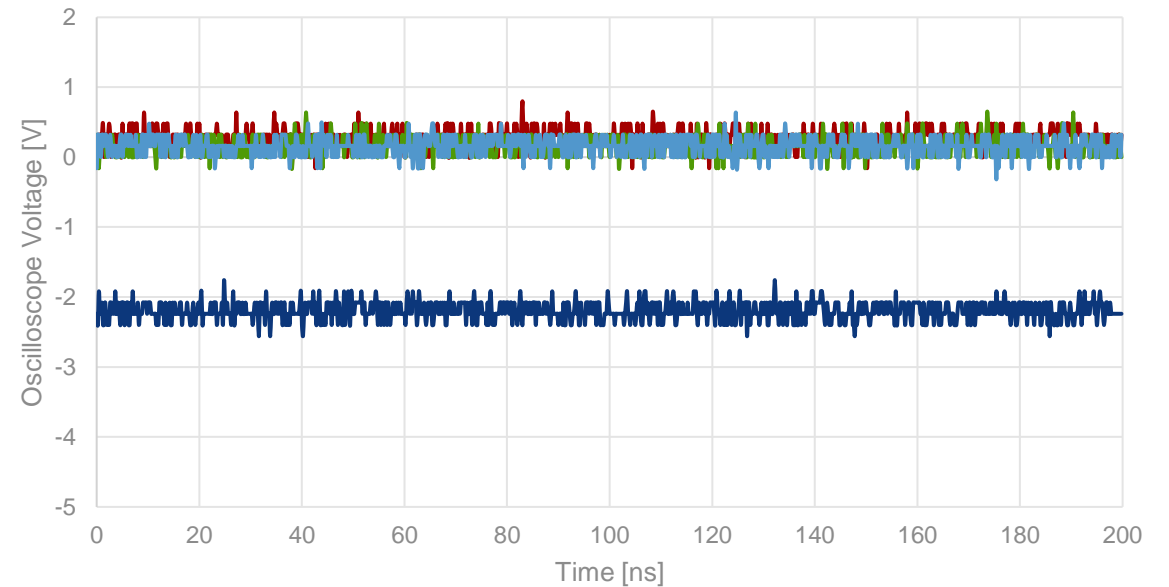
# Destructive and partially destructive SEE

- 600V PGA26E07BA, **one destructive event** detected. Effect is the short-circuit of drain and source. No gate damage. GS66508P no events.
- 100V EPC2045, **two partially destructive events**, due to leakage current increase by two orders of magnitude. No gate damage. GS61008P no events.

Destructive SEB PGA26E07BA

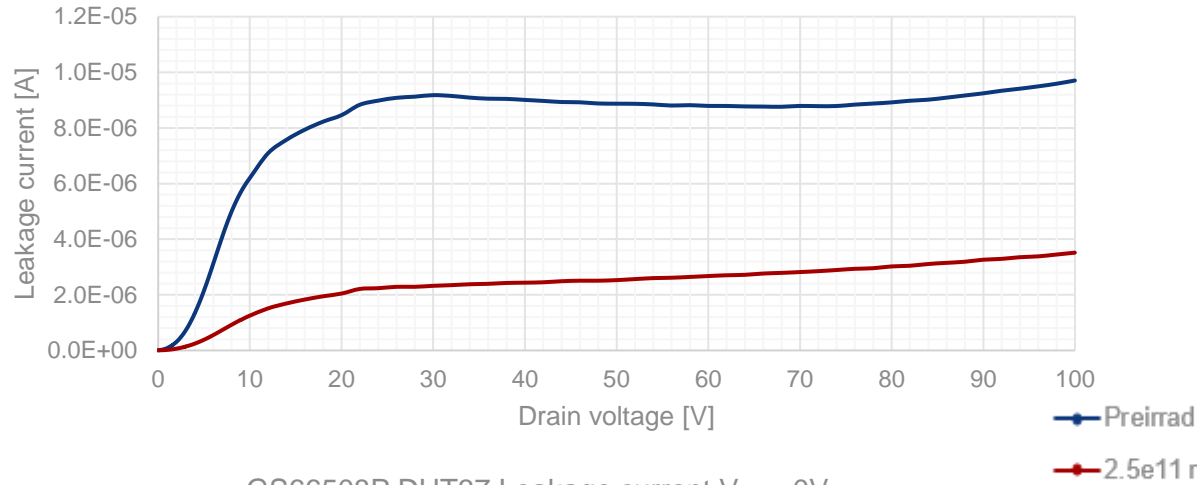


Partially destructive event EPC2045

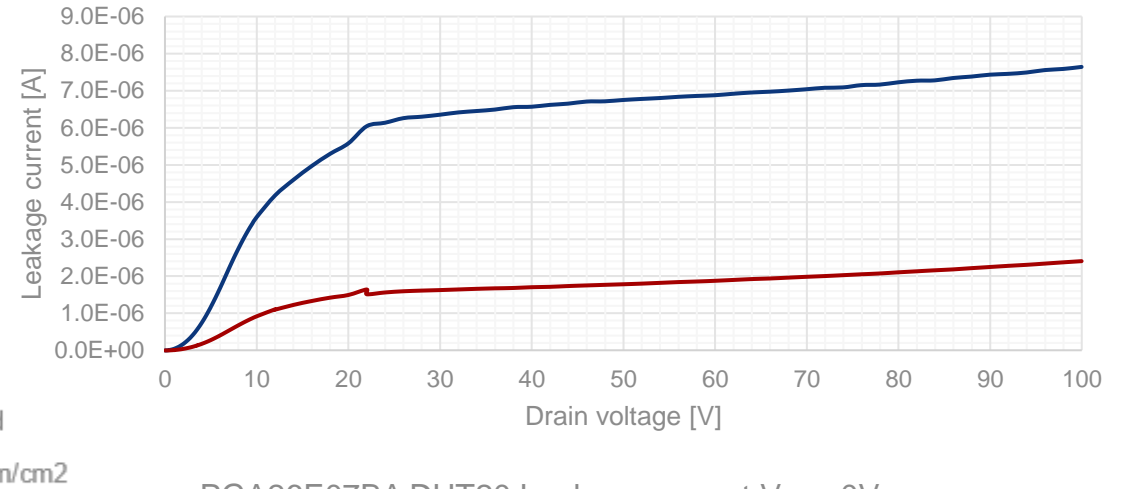


# Cumulative effects. Leakage current.

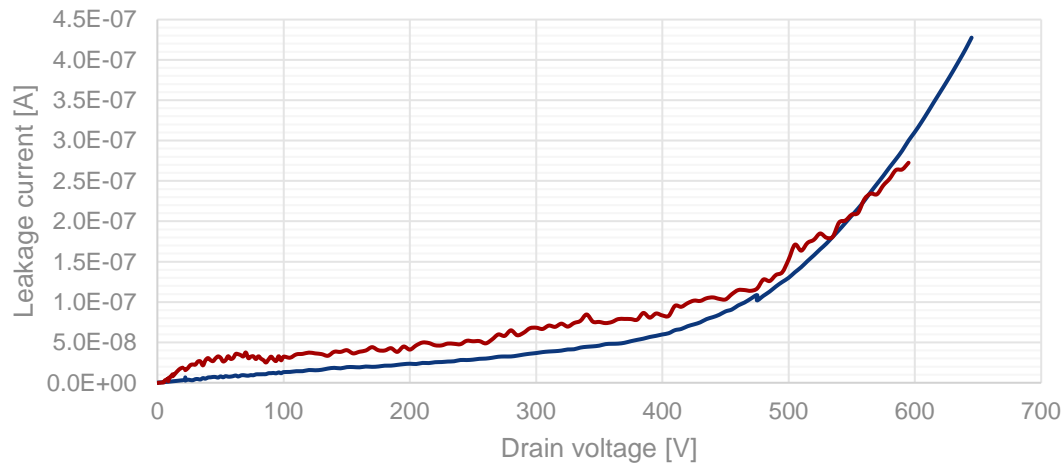
EPC2045 DUT27 Leakage current  $V_{gs} = 0V$



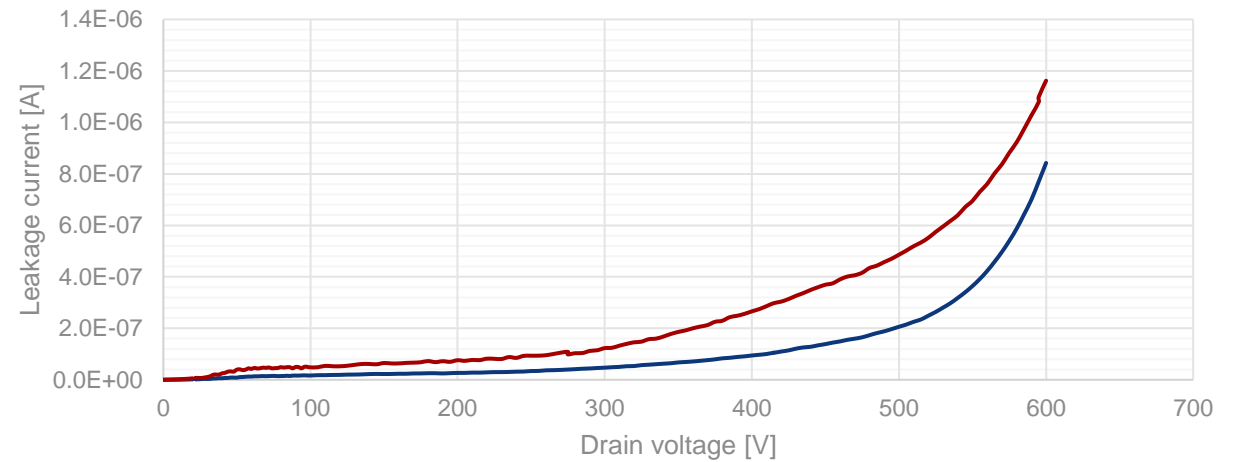
EPC2045 DUT22 Leakage current  $V_{gs} = 0V$



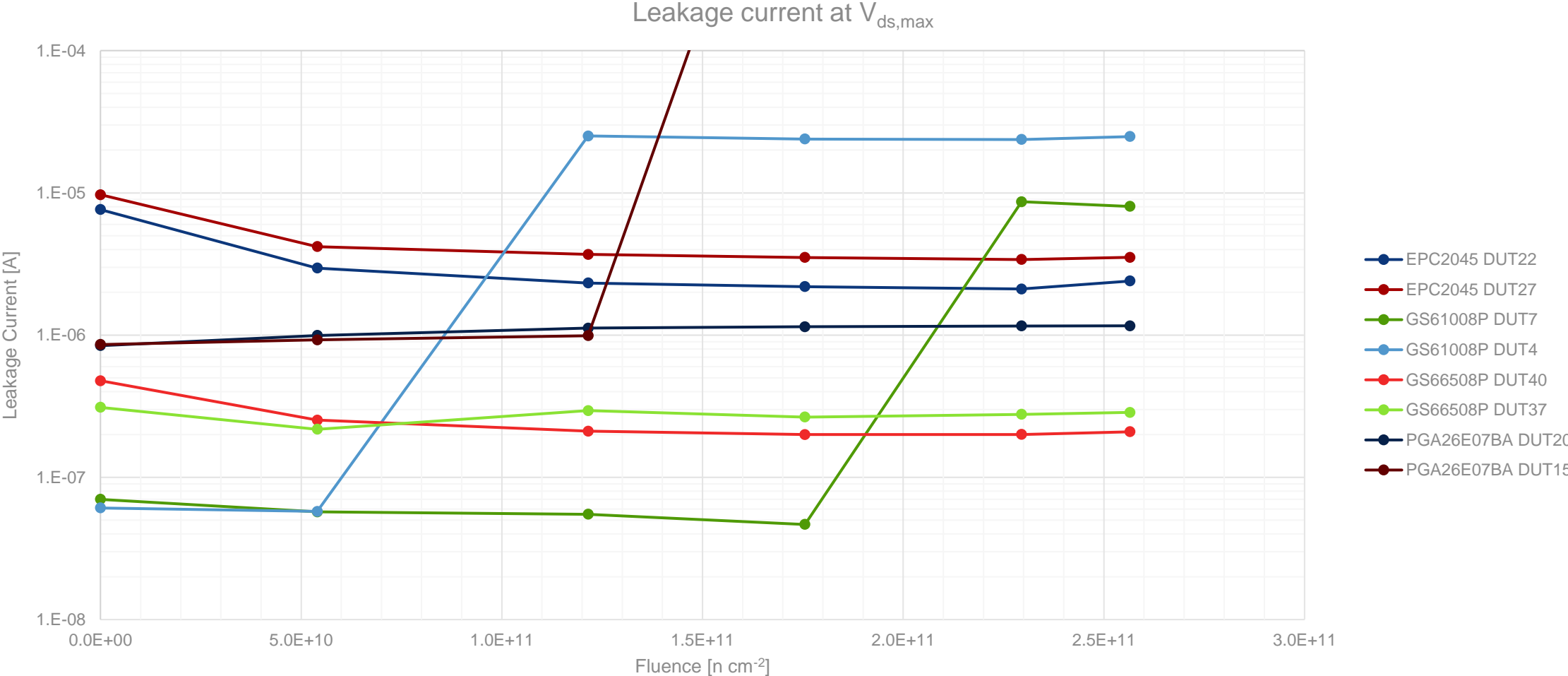
GS66508P DUT37 Leakage current  $V_{gs} = 0V$



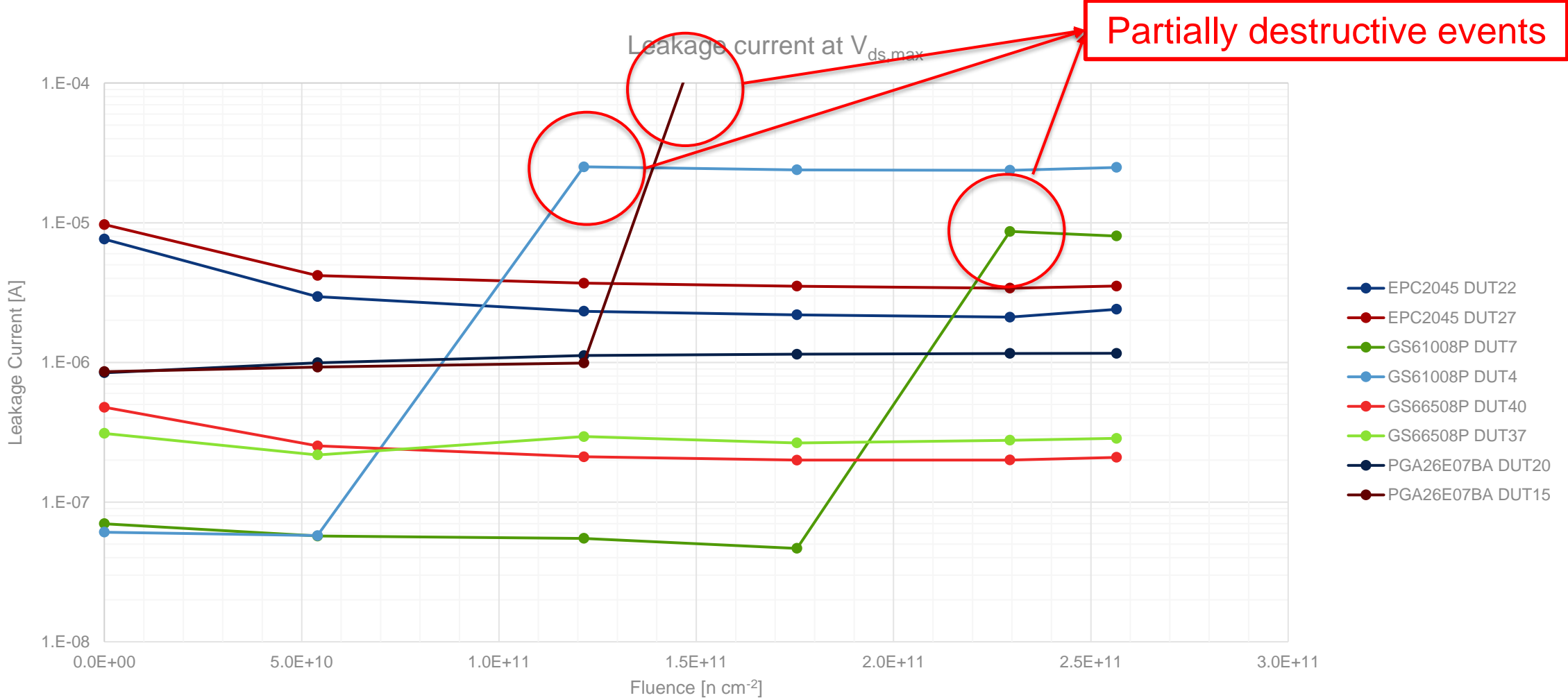
PGA26E07BA DUT20 Leakage current  $V_{gs} = 0V$



# Cumulative effects. Leakage current.

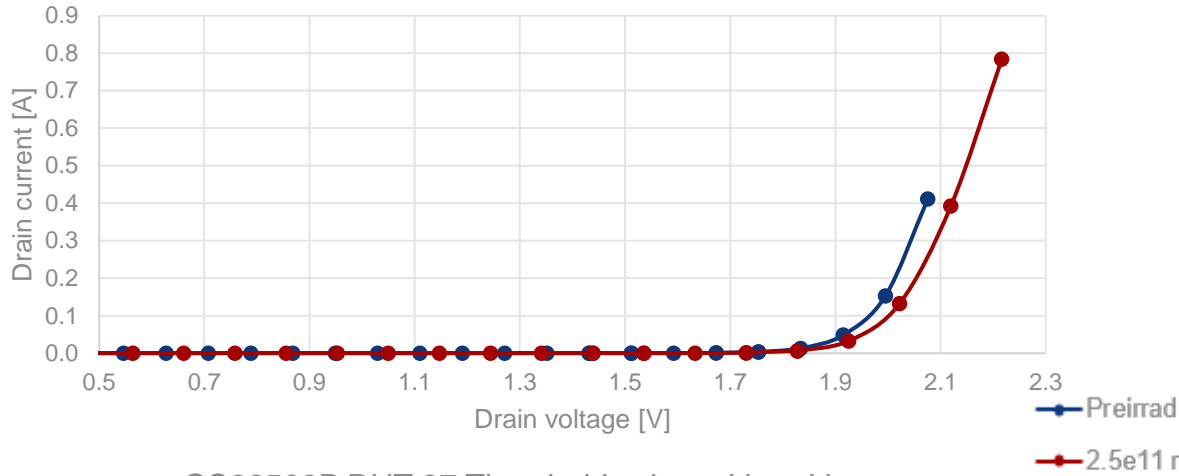


# Cumulative effects. Leakage current.

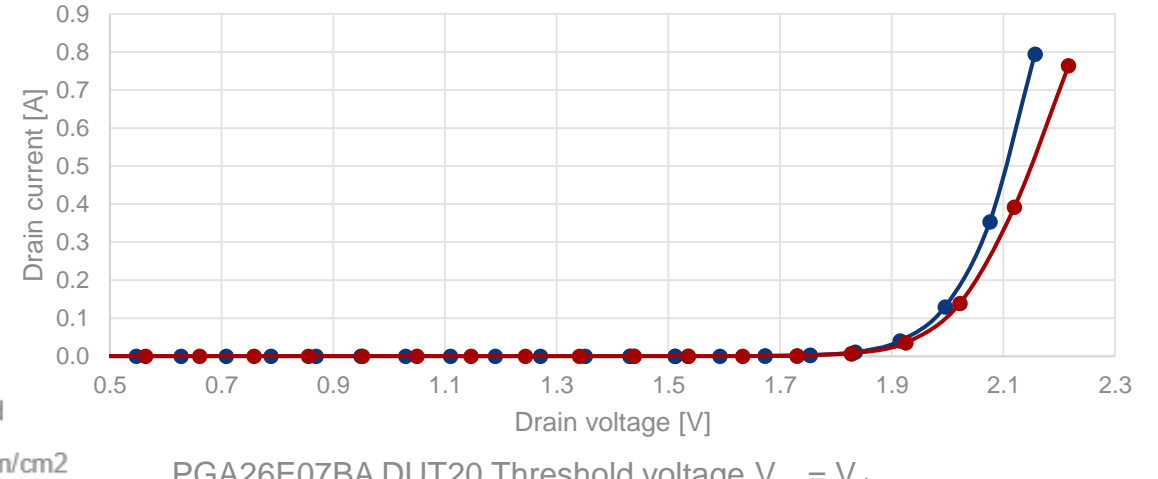


# Cumulative effects. Threshold voltage.

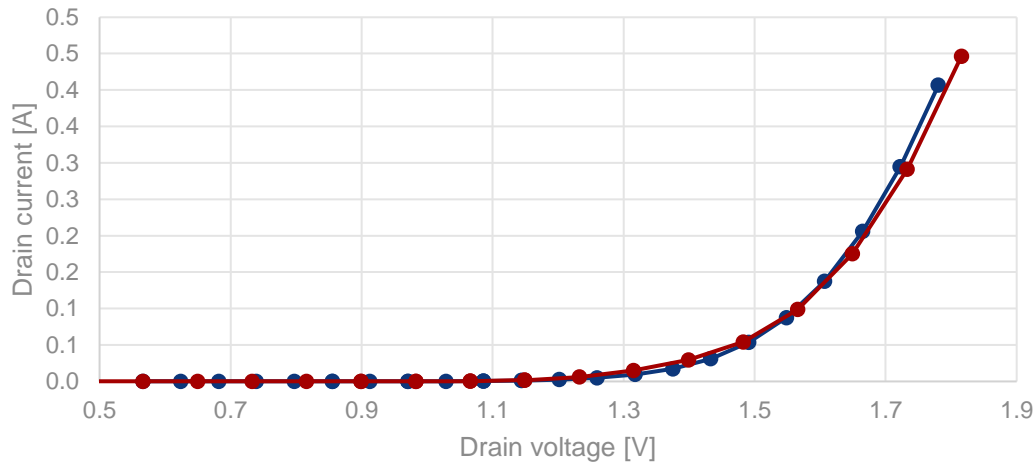
EPC2045 DUT 27 Threshold voltage  $V_{gs} = V_{ds}$



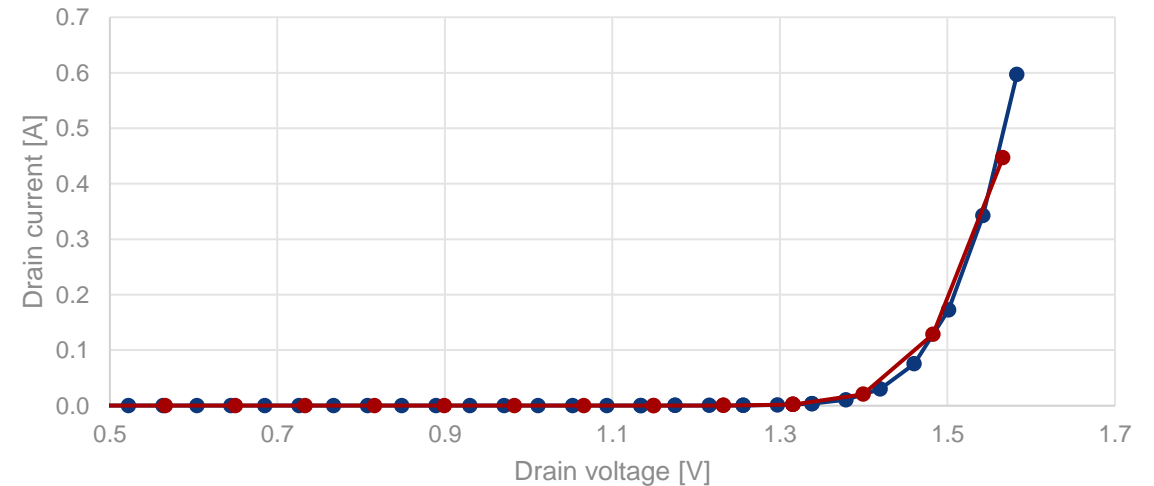
EPC2045 DUT 22 Threshold voltage  $V_{gs} = V_{ds}$



GS66508P DUT 37 Threshold voltage  $V_{gs} = V_{ds}$

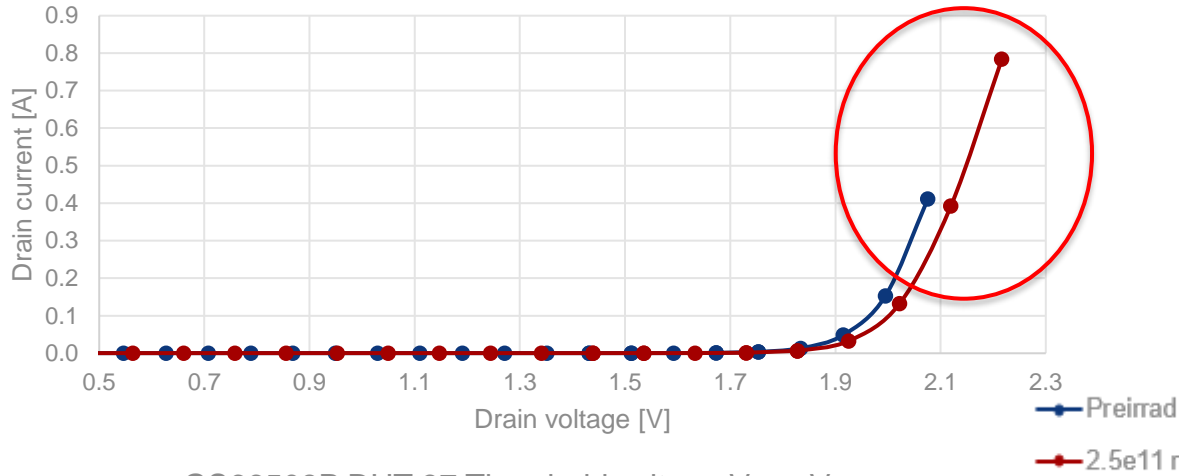


PGA26E07BA DUT20 Threshold voltage  $V_{gs} = V_{ds}$

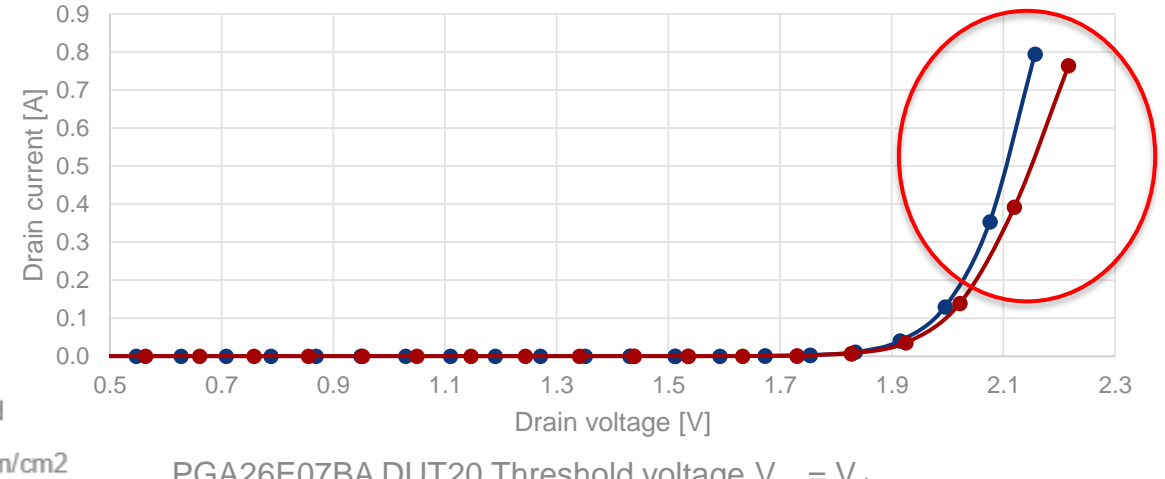


# Cumulative effects. Threshold voltage.

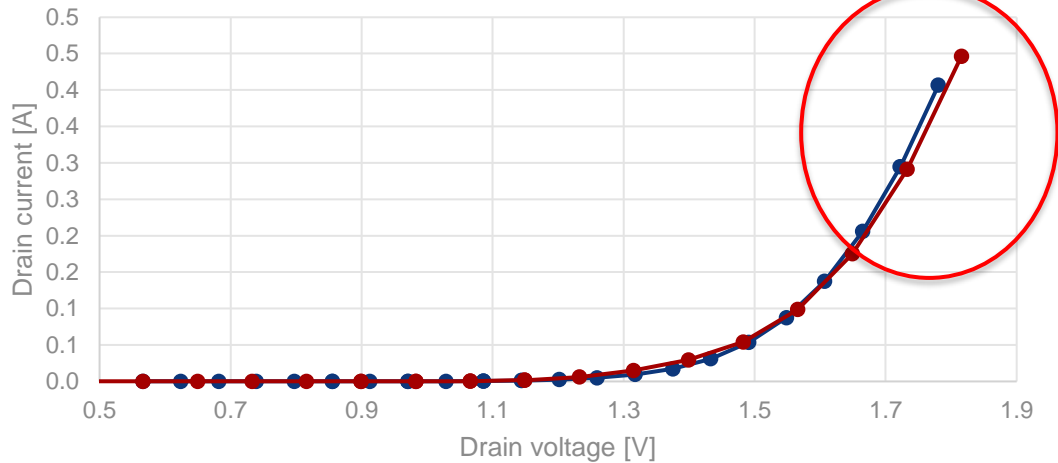
EPC2045 DUT 27 Threshold voltage  $V_{gs} = V_{ds}$



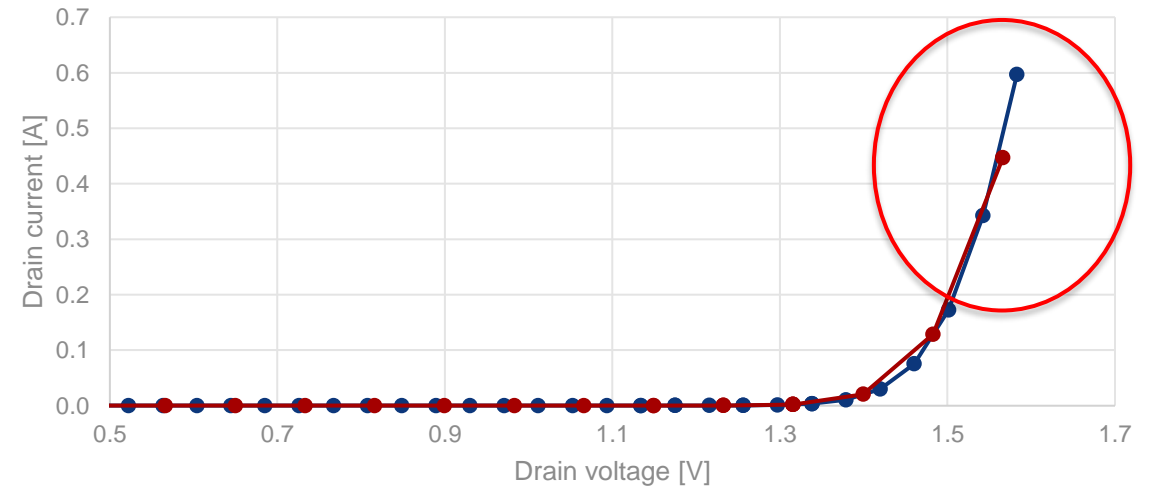
EPC2045 DUT 22 Threshold voltage  $V_{gs} = V_{ds}$



GS66508P DUT 37 Threshold voltage  $V_{gs} = V_{ds}$



PGA26E07BA DUT20 Threshold voltage  $V_{gs} = V_{ds}$





# Conclusions and future work

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- **GaN HEMTs** (x4@100V and x4@600V) have been tested in ChipIR up to  **$2.5e11 \text{ n cm}^{-2} \text{ s}^{-1}$** .
- No destructive events observed in 100V devices. One destructive events in 600V devices one, setting **cross sections in the order of  $1e-11 \text{ cm}^2$**  at 100%  $V_{ds}$ .
- Cumulative damage by neutrons is very limited, with a slight **decrease in leakage current**, **no effect on the threshold voltage** and a **decrease in transconductance** for large gate voltages.
- **Further testing SEE** with protons/heavy ions and **TID** with gamma rays.
- Characterisation of the devices to **check room temperature annealing**.
- Need to **correlate radiation effects with existing technologies** for substrates and gate structures of GaN HEMTs.
- **Special acknowledgments to Maria Kastriotou and Carlo Cazzaniga** from ChipIR without whom the campaign would not have been possible.

Thank you for  
your attention!

[mario.sacristan.barbero@cern.ch](mailto:mario.sacristan.barbero@cern.ch)



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